

**Electronic Patent Application Fee Transmittal****Application Number:**

10593857

**Filing Date:**

22-Sep-2006

**Title of Invention:**

PLASMA CHAMBER HAVING PLASMA SOURCE COIL AND METHOD FOR ETCHING THE WAFER USING THE SAME

**First Named Inventor/Applicant Name:**

Nam Hun Kim

**Filer:**

Peter C. Hsueh/Shelley Johnson

**Attorney Docket Number:**

58409/N305

Filed as Large Entity

**U.S. National Stage under 35 USC 371 Filing Fees****Description****Fee Code****Quantity****Amount****Sub-Total in  
USD(\$)****Basic Filing:****Pages:****Claims:****Miscellaneous-Filing:****Petition:****Patent-Appeals-and-Interference:****Post-Allowance-and-Post-Issuance:**

Certificate of correction

1811

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100

**Extension-of-Time:**

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Total in USD (\$)				100